

10/706624

Classification: 219/121.430

Examiner: PASCHALL, MARK

Inventor: SHIMIZU, AKIRA, et al

GAU: 3742

Status: 30 - DOCKETED NEW CASE - READY FOR EXAMINATION

Title: METHOD FOR SEMICONDUCTOR WAFER ETCHING

Bib Data report

Application Title: METHOD FOR SEMICONDUCTOR WAFER ETCHING

Application Num:  (in phx) 10706624 **Filing Date:** 11/12/2003

Effective Filing: 11/12/2003

(Location History) (Foreign/Continuity Data)

Status: 30/DOCKETED NEW CASE - READY FOR EXAMINATION **Status Date:** 08/03/2004

Patent Number: Not Issued **Issue Date:** N/A **Date of Abandonment:** N/A
Confirmation Number: 7986 **PALM Location:**

Examiner: 61092 PASCHALL, MARK **Assignment Data:** **Group Art Unit:**
3742 **Class/Subclass:** 219/121.430

State or Country: JAPAN **Sheets/Drawing:** 1 **Total Claims:** 17
Independent Claims: 3

▼ **Inventors:**

| | | |
|-------------------------------|--------------|--------------------------|
| Last name, First name: | City: | Country or State: |
| SHIMIZU, AKIRA | TOKYO | JAPAN |
| NANBA, KUNITOSHI | TOKYO | JAPAN |

Attorneys: ALL **Attorney Docket No:** ASMJP.104DV1

Interference No: **Lost Case:** No **Unmatched Petition:** No **L&R Code:** 1



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BIBDATASHEET

CONFIRMATION NO. 7986

Bib Data Sheet

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|-----------------------------|---------------------------|--------------|------------------------|--|
| SERIAL NUMBER 10/706,624 | FILING DATE 11/12/2003 | CLASS 219 | GROUP ART UNIT 3742 | ATTORNEY DOCKET NO. ASMJP.104DV1 |
|-----------------------------|---------------------------|--------------|------------------------|--|

APPLICANTS

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** CONTINUING DATA *****

This application is a DIV of 10/068,092 02/05/2002 PAT 6,764,572

** FOREIGN APPLICATIONS *****

JAPAN 2001-056685 03/01/2001

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 02/20/2004

| Foreign Priority claimed | <input type="checkbox"/> yes <input type="checkbox"/> no | STATE OR | SHEETS | TOTAL | INDEPENDENT |
|---------------------------------|---|----------|---------|--------|-------------|
| 35 USC 119 (a-d) conditions met | <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance | COUNTRY | DRAWING | CLAIMS | CLAIMS |
| Verified and Acknowledged | Examiner's Signature _____ Initials _____ | JAPAN | 1 | 17 | 3 |

ADDRESS

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IRVINE, CA

92614

TITLE

Method for semiconductor wafer etching

| | | |
|------------|---|--|
| FILING FEE | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) |
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